

THE UNITED STATES PATENT AND TRADEMARK OFFICE

**REVOCATION AND NEW POWER OF ATTORNEY AND
CHANGE OF CORRESPONDENCE ADDRESS**

I, *Dr. Graham Fisher, Director of Intellectual Property of MEMC Electronic Materials, Inc.*, the Assignee of the entire right, title, and interest in the *U.S. Patent Application(s) and/or Patent(s) identified on the attached Schedule A*, hereby revoke all previous powers of attorney or authorizations of agent given and do hereby appoint the attorneys or agents associated with the following Customer Number, with full power of substitution and revocation, to prosecute and transact all business in the Patent and Trademark Office connected therewith for the *U.S. Patent Application(s) and/or Patent(s) listed in the attached Schedule A*:

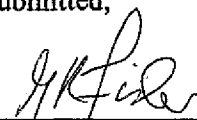
Customer Number: 76681

Please direct all correspondence in connection with said *U.S. Patent Application(s) and/or Patent(s)* to:

Customer Number: 76681

Respectfully submitted,

Date: 5/13/2008



Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

PATENT

THE UNITED STATES PATENT AND TRADEMARK OFFICE

STATEMENT UNDER 37 CFR 3.73(b)

MEMC Electronic Materials, Inc., a Delaware Corporation, pursuant to 37 CFR 3.73(b), hereby states that it is the Assignee of the entire right, title, and interest in *U.S. Patent Application(s) and/or Patent(s) on the attached Schedule A.*

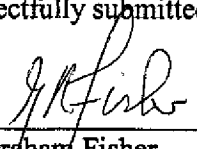
The entire rights, title, and interest in the aforementioned Patent Application(s) and/or Patent(s) were conveyed to **MEMC Electronic Materials, Inc.** via Assignment(s) recorded with the United States Patent and Trademark Office at the *Reel/Frame Numbers on the attached Schedule A.*

The undersigned, **Dr. Graham Fisher, Director of Intellectual Property**, has full authorization to act on behalf of Assignee **MEMC Electronic Materials, Inc.**

Respectfully submitted,

Date: _____

5/13/2008



Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

APPENDIX A
Owned by MEMC Electronic Materials, Inc.

ATTORNEY REFERENCE	CONF. NO	PUBLICATION NO. & DATE	SERIAL NO. FILING DATE	PATENT NO. ISSUE DATE	CURRENT OWNER/ ASSIGNEE	REEL AND FRAME NO.	TITLE
MEMC2152	4683		09/245,238 2/5/1999	6,187,089 2/13/2001	MEMC Electronic Materials, Inc.	009924/0736	TUNGSTEN DOPED CRUCIBLE AND METHOD FOR PREPARING SAME
MEMC2153	9430		09/172,546 10/14/1998	6,171,391 19/2001	MEMC Electronic Materials, Inc.	009572/0757	METHOD AND SYSTEM FOR CONTROLLING GROWTH OF A SILICON CRYSTAL
MEMC2156	1712		09/167,747 10/7/1998	6,039,801 3/21/2000	MEMC Electronic Materials, Inc.	009612/0596	CONTINUOUS OXIDATION PROCESS FOR CRYSTAL PULLING APPARATUS
MEMC2172	3315		09/082,906 5/21/1998	6,482,289 11/19/2002	MEMC Electronic Materials, Inc.	009307/0116	PROCESS FOR THE REMOVAL OF COPPER AND OTHER METALLIC IMPURITIES FROM SILICON
MEMC2190	1889		09/276,278 3/25/1999	6,227,944 5/8/2001	MEMC Electronic Materials, Inc.	009888/0581	METHOD FOR PROCESSING A SEMICONDUCTOR WAFER
MEMC2232	2855		09/352,980 7/14/1999	6,338,805 1/15/2002	MEMC Electronic Materials, Inc.	010222/0227	PROCESS FOR FABRICATING SEMICONDUCTOR WAFERS WITH EXTERNAL GETTERING
MEMC2235.1	2260		09/596,493 6/19/2000	6,458,202 10/1/2002	MEMC Electronic Materials, Inc.	011107/0117	PROCESS FOR PREPARING SINGLE CRYSTAL SILICON HAVING UNIFORM THERMAL HISTORY
MEMC2246	1848		09/345,334 7/11/1999	6,231,626 5/15/2001	MEMC Electronic Materials, Inc.	010256/0143	METHOD FOR THE SEPARATION, REGENERATION AND REUSE OF AN EXHAUSTED GLYCOL-BASED SLURRY
MEMC2289	3920		09/258,478 2/26/1999	6,197,111 3/6/2001	MEMC Electronic Materials, Inc.	009939/0094	HEAT SHIELD ASSEMBLY FOR CRYSTAL PULLER
MEMC2292	9868		09/607,391 6/30/2000	6,599,815 7/29/2003	MEMC Electronic Materials, Inc.	011185/0935	A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A DENUDED ZONE
MEMC2294	9859		09/607,389 6/30/2000	6,339,016 1/15/2002	MEMC Electronic Materials, Inc.	011186/0967	METHOD AND APPARATUS FOR FORMING AN EPITAXIAL SILICON WAFER WITH A DENUDED ZONE
MEMC2340.1	4591	US 2002-0056410 A1 5/16/2002	09/972,608 10/5/2001	6,858,307 2/22/2005	MEMC Electronic Materials, Inc.	012409/0073	METHOD FOR THE PRODUCTION OF LOW DEFECT DENSITY SILICON
MEMC2340.10	8176	US-2005-0132948-A1 6/23/2005	11/058,885 2/16/2005	7,105,050 9/12/2006	MEMC Electronic Materials, Inc.	Division of 09/972,608 recorded at 012409/0073	METHOD FOR THE PRODUCTION OF LOW DEFECT DENSITY SILICON
MEMC2345	2610		09/250,908 2/16/1999	6,284,384 9/4/2001	MEMC Electronic Materials, Inc.	009906/0976	EPITAXIAL SILICON WAFER WITH INTRINSIC GETTERING
MEMC2345.1	3949	US 2001-0032581 A1 10/25/2001	09/859,094 5/16/2001	6,537,655 3/25/2003	MEMC Electronic Materials, Inc.	Division of 09/250,908 recorded at 009906/0976	EPITAXIAL SILICON WAFER WITH INTRINSIC GETTERING AND A METHOD FOR THE PREPARATION THEREOF
MEMC2345.2	3292	US2005-0098092 A1 5/12/2005	10/400,594 3/25/2003	6,958,092 10/25/2005	MEMC Electronic Materials, Inc.	Division of 09/859,094 which is a division of 09/250,908 recorded at 009906/0976	EPITAXIAL SILICON WAFER WITH INTRINSIC GETTERING AND A METHOD FOR THE PREPARATION THEREOF
MEMC2352	6473		09/234,144 1/19/1999	6,053,974 4/25/2000	MEMC Electronic Materials, Inc.	Division of 08/940,166 recorded at 008734/0188	HEAT SHIELD FOR CRYSTAL PULLER